Driving Down HB-LED Costs (Part 2): Advanced Chemistry Models for MOCVD Reactor Design/Optimization

Project title:

Driving Down HB-LED Costs: Implementation of Process Simulation Tools and Temperature Control for High Yield MOCVD Growth

Team Members:

Veeco Instruments, Sandia National Laboratories, Philips Lumileds

Overall Goal:

Reduce LED cost by 4x through increased MOCVD growth yield, improved efficiency, and better productivity

Manufacturing R&D MYPP targets:

A4.4 Manufacturing simulation; B4.1 Yield manufacturability;

B4.2 Epitaxial growth; B4.3 Manufacturing tools

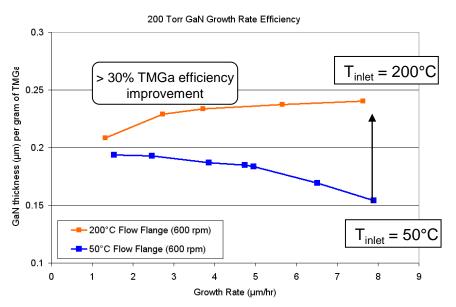






Heated Flow Flange GaN Growth Source Efficiency

At a gas inlet temperature of 200°C, metal organic efficiency increases by more than 30% at high growth rates of GaN



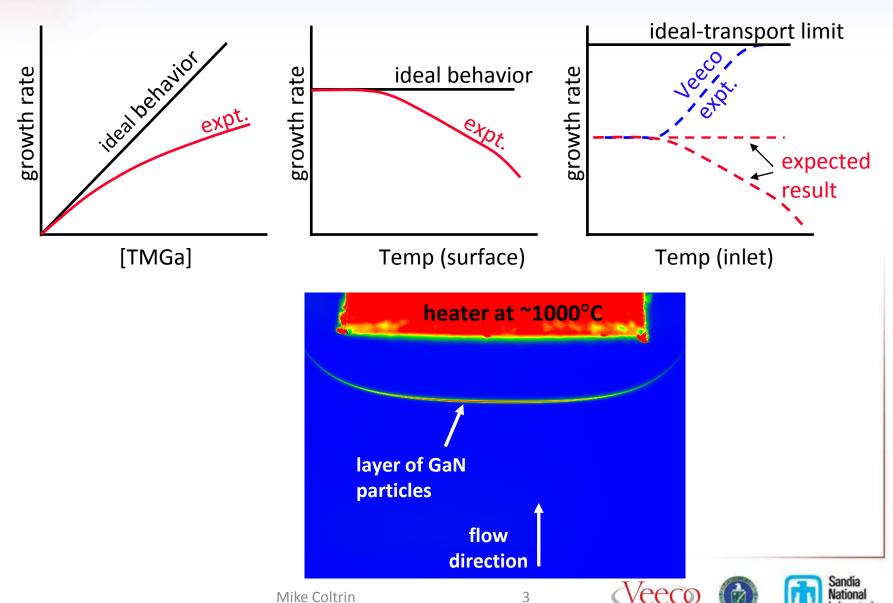
GaN growth rate as a function of TMGa flow and Flow Flange™ temperature 7.0 200°C, 300 Torr, 1000 rpm $T_{inlet} = 200$ °C 200°C, 400 Torr, 750 rpm 6.0 200°C, 500 Torr, 600 rpm 50°C, 300 Torr, 1000 rpm 50°C, 500 Torr, 600 rpm $T_{inlet} = 50^{\circ}$ 1.0 0.0 0 100 200 300 400 500 600 700 TMGa flow (sccm at 800 Torr, 15°C)







Growth Rates Dominated by Gas-Phase Particle Chemistry



Particle Formation Explains MOCVD Growth Rate Behavior

